Docket No.: M4065.0369/P369 Micron No.: 00-566

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE DECLARATION FOR PATENT APPLICATION

As the below named inventor, I hereby declare that:

My residence, post office address and citizenship are as stated below next to my name.

I believe I am the original, first and sole inventor of the subject matter which is claimed and for which a patent is sought on the invention entitled:

METHOD AND COMPOSITION FOR PLASMA ETCHING OF A SELF-ALIGNED CONTACT OPENING

The specification of which is attached hereto.

I hereby state that I have reviewed and understand the contents of the above identified specification, including the claims, as amended by an amendment, if any, specifically referred to in this oath or declaration.

I acknowledge the duty to disclose all information known to me which is material to patentability as defined in Title 37, Code of Federal Regulations, § 1.56.

I hereby claim foreign priority benefits under Title 35, United States Code § 119/365 of any foreign application(s) for patent or inventor's certificate listed below and have also identified below any foreign application for patent or inventor's certificate having a filing date before that of the application on which priority is claimed:

Prior Foreign Application(s)		Priority Not Claimed	
(Number)	(Country)	(Filing Date)	
(Number)	(Country)	(Filing Date)	
(Number)	(Country)	(Filing Date)	

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I hereby claim the benefit under Title 35, United States Code, § 120/365 of any United States and PCT international application(s) listed below and, insofar as the subject matter of each of the claims of this application is not disclosed in the prior United States application in the manner provided by the first paragraph of Title 35, United States Code, § 112, I acknowledge the duty to disclose all information known to me to be material to patentability as defined in Title 37, Code of Federal Regulations, § 1.56(a) which became available between the filing date of the prior application and the national or PCT international filing date of this application:

(Application Serial No.)	(Filing Date) (Status)	
		(patented, pending, abandoned)
(Application Serial No.)	(Filing Date)	(Status)
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		(patented, pending, abandoned)
(Application Serial No.)	(Filing Date)	(Status)
		(patented, pending, abandoned)

I hereby declare that all statements made herein of my own knowledge are true and that all statements made on information and belief are believed to be true; and further that these statements were made with the knowledge that willful false statements and the like so made are punishable by fine or imprisonment, or both, under Section 1001 of Title 18 of the United States Code and that such willful false statements may jeopardize the validity of the application or any patent issued thereon.

Please address all correspondence to Thomas J. D'Amico of Dickstein Shapiro Morin & Oshinsky LLP located at 2101 L Street NW. Telephone calls should be made to (202) 785-9700.

Full name of inventor: Shane J. Trapp

Inventor's signature:

Mrs. Japp Date: 17/18/00

Residence:

Boise, Idaho

Citizenship:

United States of America

Post Office Address:

1760 E. Victory

Boise, Idaho 83706

Micron Docket No.: 00-566 Docket No.: M4065.0369/P369

(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Shane J. Trapp

Serial No.: Not Yet Assigned

Group Art Unit: N/A

Filed: Concurrently Herewith

Examiner: Not Yet Assigned

For: METHOD AND COMPOSITION FOR PLASMA ETCHING OF A SELF-ALIGNED

CONTACT OPENING

POWER OF ATTORNEY BY ASSIGNEE AND CERTIFICATE BY ASSIGNEE UNDER 37 CFR § 3.73(B)

Assistant Commissioner for Patents Washington, DC 20231

Dear Sir:

Micron Technology, Inc., Assignee of the entire right, title and interest in the above-identified application by virtue of the Assignment attached hereto (which is also being submitted concurrently for recordation), hereby appoints the attorneys and agents of the firm of Dickstein Shapiro Morin & Oshinsky LLP located at 2101 L Street NW, Washington, DC 20037-1526, listed as follows:

, and also, attorneys of Micron Technology, Inc. as its attorneys with full power of substitution to prosecute this application and to transact all business in the Patent and Trademark Office in connection therewith.

The Assignee certifies that the above-identified assignment has been reviewed and to the best of the Assignee's knowledge and belief, title is in the assignee.

Please direct all correspondence regarding this application to the following:

Thomas J. D'Amico DICKSTEIN SHAPIRO MORIN & OSHINSKY LLP 2101 L Street NW Washington, DC 20037-1526 (202) 785-9700 (202) 861-9106

Respectfully submitted,

MICRON TECHNOLOGY, INC.

Michael L. Lynch

Chief Patent Counsel Registration No. 30,871

Dated: /

12-26-200r